This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF CLAIMS:

1. (Currently Amended) A polymer containing a group of the following general formula (1) and having a weight average molecular weight of 1,000 to 500,000,

$$R_2$$
 R_3
 R_4
 R_6
 R_7
 R_1
 R_3
 R_4
 R_6
 R_7
 R_7

wherein R¹ to R³-each are <u>is</u> hydrogen, fluorine or a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms, <u>and</u> R² and R³ may bond together to form a ring and in that event, <u>such that</u> each is an alkylene group of 1 to 20 carbon atoms which may contain a <u>optionally contains an oxygen</u>, <u>sulfur or nitrogen</u> hetero atom <u>such as oxygen</u>, <u>sulfur or nitrogen</u>,

R⁴ and R⁵ each are hydrogen or fluorine,

 R^6 and R^7 each are hydrogen, fluorine or a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms, at least one of R^6 and R^7 contains at least one fluorine atom, or alternatively R^6 and R^7 may bond together to form a ring and in that event.

each is a straight, branched or cyclic alkylene or fluorinated alkylene group of 1 to 20 carbon atoms, and

"a" is 0 or 1.

2. (Currently Amended) The A polymer of claim 1 containing a group of the following general formula (1a) and having a weight average molecular weight of 1,000 to 500,000:

$$R_2$$
 R_2
 R_3
 R_4
 R_5
 R_7
 R_7

wherein R¹ to R³ each are hydrogen, fluorine or a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms, or alternatively R² and R³ may bond together to form a ring and in that event, each is an alkylene group of 1 to 20 carbon atoms which may eontain optionally contains a hetero atom such as oxygen, sulfur or nitrogen, "a" is 0 or 1, and "b" is an integer of 1 to 4.

3. (Currently Amended) The polymer of claim 1 having a partial structure of any one of the following general formulae (2-1) to (2-5):

wherein R⁰ is a group of formula (1) in claim 1 or a group of formula (1a) in claim 2,

R⁸ to R¹⁰ each are hydrogen, fluorine or a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms,

R¹¹ is a methylene group, oxygen atom or sulfur atom,

R¹² and R¹³ each are hydrogen, methyl or CH₂CO₂R¹⁵,

R¹⁴ is a straight, branched or cyclic alkylene or fluorinated alkylene group of 1 to 20 carbon atoms,

R¹⁵ is a straight, branched or cyclic alkyl or substituted alkyl group of 1 to 20 carbon atoms, and

"c" is 0 or 1.

- 4. (Original) A resist composition comprising the polymer of claim 1.
- 5. (Previously presented) A chemically amplified, positive resist composition comprising
 - (A) the polymer of claim 1,
 - (B) an organic solvent, and
 - (C) a photoacid generator.
- 6. (Original) The resist composition of claim 5 further comprising (D) a basic compound.
- 7. (Original) The resist composition of claim 5 further comprising (E) a dissolution inhibitor.
- 8. (Original) A process for forming a resist pattern comprising the steps of:

 applying the resist composition of claim 4 onto a substrate to form a coating,

 heat treating the coating and then exposing it to high-energy radiation in a wavelength

 band of 100 to 180 nm or 1 to 30 nm through a photo mask, and

 optionally heat treating the exposed coating and developing it with a developer.

- 9. (Original) The pattern forming process of claim 8 wherein the high-energy radiation is an F_2 laser beam, Ar_2 laser beam or soft x-ray.
- 10. (New) The polymer of claim 3 which additionally comprises recurring units of one of formulae (3-1) to (3-5):

wherein, R^8 to R^{15} and c are as defined above, and R^{16} is an acid labile group.

11. (New) The polymer of claim 2 having a partial structure of any one of the following formulae (2-1) to (2-5):

$$R_{11}$$
 R_{11}
 R_{11}
 R_{11}
 R_{11}
 R_{11}
 R_{12}
 R_{12}
 R_{13}
 R_{14}
 R_{14}
 R_{14}
 R_{14}
 R_{14}
 R_{14}
 R_{14}
 R_{15}
 R_{10}
 R

wherein R⁰ is a group of formula (1a) in claim 2,

R⁸ to R¹⁰ each are hydrogen, fluorine or a straight, branched or cyclic alkyl or fluorinated alkyl group of 1 to 20 carbon atoms,

R¹¹ is a methylene group, oxygen atom or sulfur atom,

R¹² and R¹³ each are hydrogen, methyl or CH₂CO₂R¹⁵,

R¹⁴ is a straight, branched or cyclic alkylene or fluorinated alkylene group of 1 to 20 carbon atoms,

R¹⁵ is a straight, branched or cyclic alkyl or substituted alkyl group of 1 to 20 carbon atoms, and

"c" is 0 or 1.

12. (New) A resist composition comprising the polymer of claim 2.

- 13. (New) A chemically amplified, positive resist composition comprising
 - (A) the polymer of claim 2,
 - (B) an organic solvent, and
 - (C) a photoacid generator.
- 14. (New) The resist composition of claim 13 further comprising (D) a basic compound.
- 15. (New) The resist composition of claim 13 further comprising (E) a dissolution inhibitor.
- 16. (New) A process for forming a resist pattern comprising the steps of:

 applying the resist composition of claim 12 onto a substrate to form a coating,

 heat treating the coating and then exposing it to high-energy radiation in a wavelength
 band of 100 to 180 nm or 1 to 30 nm through a photo mask, and

 optionally heat treating the exposed coating and developing it with a developer.
- 17. (New) The pattern forming process of claim 16 wherein the high-energy radiation is an F₂ laser beam, Ar₂ laser beam or soft x-ray.
- 18. (New) The polymer of claim 11 which additionally comprises one or more recurring units of one of formulae (3-1) to (3-5):

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wherein, R⁸ to R¹⁵ and c are as defined above, and R¹⁶ is an acid labile group.

19. (New) The polymer of claim 3 which additional comprises one or more recurring units of one of the formulae (7-1) to (7-5)

wherein, R^8 to R^{15} and c are as defined above, and R^{29} is a fluorinated alkyl group having 2 to 20 carbon atoms.

20. (New) The polymer of claim 3 which additional comprises one or more recurring units of one of the formulae (8-1) to (8-5):

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wherein, R⁸ to R¹⁵ and c are as defined above, and R³⁰ is hydrogen or an adhesive group.

21. (New) The polymer of claim 11 which additional comprises one or more recurring units of one of the formulae (7-1) to (7-5)

wherein, R^8 to R^{15} and c are as defined above, and R^{29} is a fluorinated alkyl group having 2 to 20 carbon atoms.

22. (New) The polymer of claim 11 which additional comprises one or more recurring units of one of the formulae (8-1) to (8-5):

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wherein, R⁸ to R¹⁵ and c are as defined above, and R³⁰ is hydrogen or an adhesive group.